



IFW

Docket No. IT601US

MAIKP131US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re **PATENT** application of:

Applicant: Huang et al.

Serial No.: 10/814,570

For: PROCESS FOR ETCHING A SUBSTRATE (as translated)

Filing Date: March 31, 2004

Examiner: (presently unknown)

Art Unit: (presently unknown)

PRELIMINARY AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following remarks.